

FPD Materials & Components Japan TC Chapter and FPD Metrology Japan TC Chapter Joint Meeting Meeting Summary and Minutes

SEMI Japan Standards Fall 2014 Meetings
October 30, 2014, 14:30-17:00
SEMI Japan, Tokyo, Japan

Next Committee Meeting
FPD Materials & Components Japan TC Chapter:
SEMI Japan Standards Winter 2015 Meetings
Friday, February 6, 2015, 15:00-17:00
SEMI Japan, Tokyo, Japan

FPD Metrology Japan TC Chapter:
SEMI Japan Standards Spring 2015 Meetings
Friday, April 10, 2015, 14:00-17:00
SEMI Japan, Tokyo, Japan

Table 1 Meeting Attendees

Co-Chairs of FPD M&C Committee: Tadahiro Furukawa (Yamagata University), Yoshi Shibahara (Fujifilm)
Co-Chairs of FPD Metrology Committee: Ryoichi Watanabe (Japan Display), Akira Kawaguchi (Otsuka Electronics)
SEMI Staff: Naoko Tejima (SEMI Japan)

<i>Company</i>	<i>Last</i>	<i>First</i>	<i>Company</i>	<i>Last</i>	<i>First</i>
Yamagata University	Furukawa	Tadahiro	Corning International	Okamura	Haruo
Teijin	Itoh	Haruhiko	Fujifilm	Shibahara	Yoshi
Corning Holding Japan	Kashima	Yasumasa	SK Electronics	Shiojiri	Kazuya
Otsuka Electronics	Kawaguchi	Akira	Sony	Tomioka	Satoshi
HOYA	Nitobe	Kaname	Japan Display	Watanabe	Ryoichi
SK Electronics	Nogami	Yoshitada	SEMI Japan	Tejima	Naoko

** alphabetical order by last name*

Table 2 Leadership Changes

FPD Materials & Components Japan TC Chapter

<i>Group</i>	<i>Previous Leader</i>	<i>New Leader</i>
Backlight Task Force was disbanded	Satoshi Kanazawa (Stanley Electric) Masami Takagi (Toshiba Lighting & Technology) Kazuyoshi Yamaguchi (-)	None.

FPD Metrology Japan TC Chapter

None.

Table 3 Ballot Results

Passed ballots and line items will be forwarded to the ISC Audit & Review Subcommittee for procedural review.
Failed ballots and line items were returned to the originating task forces for re-work and re-balloting.

FPD Materials & Components Japan TC Chapter

<i>Document #</i>	<i>Document Title</i>	<i>Committee Action</i>
5550	New Standard: Guide for Measuring Dimensions for Plastic Films/Substrates	Passed as balloted
5696	Reapproval of SEMI D9-0303 (Reapproved 0709), Terminology for FPD Substrates	Passed as balloted

FPD Metrology Japan TC Chapter

None.

Table 4 Authorized Ballots

FPD Materials & Components Japan TC Chapter

<i>Document #</i>	<i>When</i>	<i>SC/TF/WG</i>	<i>Details</i>
5796	Cycle8, 2014	FPD Mask TF	Reapproval of SEMI D20-0706 Terminology for FPD Mask Defect
5797	Cycle8, 2014	FPD Mask TF	Reapproval of SEMI D21-0706 Terminology for FPD Mask Pattern Accuracy
5798	Cycle8, 2014	FPD Mask TF	Reapproval of SEMI D42-0308 Specification for Ultra Large Size Mask Substrate Case
5799	Cycle8, 2014	FPD Mask TF	Reapproval of SEMI D53-0308 Specification for Liquid Crystal Display (LCD) Pellicles

FPD Metrology Japan TC Chapter

None.

Table 5 Authorized Activities

FPD Materials & Components Japan TC Chapter

<i>Document #</i>	<i>Type</i>	<i>SC/TF/WG</i>	<i>Details</i>
5796	SNARF	FPD Mask TF	Reapproval of SEMI D20-0706 Terminology for FPD Mask Defect
5797	SNARF	FPD Mask TF	Reapproval of SEMI D21-0706 Terminology for FPD Mask Pattern Accuracy
5798	SNARF	FPD Mask TF	Reapproval of SEMI D42-0308 Specification for Ultra Large Size Mask Substrate Case
5799	SNARF	FPD Mask TF	Reapproval of SEMI D53-0308 Specification for Liquid Crystal Display (LCD) Pellicles

FPD Metrology Japan TC Chapter

None.

Table 6 New Action Items
FPD M&C Japan TC Chapter

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>
FPD M&C141030-01	SEMI Staff	To correct “Meeting Attendees” and “New Action Items # FPD M&C 140418-01” of the previous meeting minutes.
FPD M&C 141030-02	SEMI Staff	To forward adjudication result of Doc.#5550 to the ISC A&R Subcommittee for procedural review.
FPD M&C 141030-03	SEMI Staff	To forward adjudication result of Doc.#5696 to the ISC A&R Subcommittee for procedural review.
FPD M&C 141030-04	SEMI Staff	To submit reapproval ballot of SEMI D20 (#5796) for Cycle 8, 2014.
FPD M&C 141030-05	SEMI Staff	To submit reapproval ballot of SEMI D21 (#5797) for Cycle 8, 2014.
FPD M&C 141030-06	SEMI Staff	To submit reapproval ballot of SEMI D42 (#5798) for Cycle 8, 2014.
FPD M&C 141030-07	SEMI Staff	To submit reapproval ballot of SEMI D53 (#5799) for Cycle 8, 2014.

FPD Metrology Japan TC Chapter

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>
FPD MET 141030-01	SEMI Staff	To correct “Meeting Attendees” of the previous meeting minutes.

[Common Part 1]

1 Welcome, Reminders, and Introductions

Tadahiro Furukawa, committee co-chair, called the meeting to order at 14:30. Self-introductions were made followed by the agenda review.

2 Required Meeting Elements

The meeting reminders on antitrust issues, intellectual property issues and holding meetings with international attendance were reviewed by SEMI staff, Naoko Tejima.

3 SEMI Staff Report

Naoko Tejima gave the SEMI staff report. This report included PV Automation TC Transformation to Automation Technology TC, Guidance for Task Force Meeting Operation, SEMI Global 2014 & 2015 Calendar of Events, Global Standards Meetings Schedule, SEMICON Japan Information & Meeting Schedule, 2014 Critical Dates for SEMI Standards Ballots, SEMI Standards Publication, A&R Ballot Review and Contact Information.

Attachment: 01_SEMI_Staff_Report_141030

Attachment: 02_Task_Force_Operation_Guideline_141030

4 Liaison Reports

4.1 Korea FPD Committee Report

Naoko Tejima reported for the Korea FPD Metrology Committee. This report included Leadership, Organization Chart, Meeting Information, Ballot Review Result, Technical Ballots to be reviewed at SEMICON Korea 2015 Meeting, Task Force Updates and Contact Information.

Attachment: 03_KR_FPD_Liaison_Report_141030

4.2 Taiwan FPD Committee Report

Naoko Tejima reported for the Taiwan FPD Committee. This report included Leadership, FPD Standard Committee Organization Chart, FPD Standard Committee Highlights, FPD Standard Committee and Contact Information.

Attachment: 04_TW_FPD_Liaison Report_141030

[Japan FPD Materials & Components Committee Part]

5 Review of Previous Meeting Minutes

The committee reviewed the minutes of the previous meeting held on April 18, 2014.

It was pointed the following 2 items should be changed.

- Meeting Attendees: “Haruhiko Itoh, Teijin” should be corrected to “Takashi Shiro, Teijin”.
- New Action Items # FPD M&C 140418-01: “To Contact co-leaders...” should be corrected to “ To contact Backlight Task Force co-leaders”.

Motion: To approve the minutes of the previous meeting as written after the above points are corrected.

By / 2nd: Yoshi Shibahara (Fujifilm) / Ryoichi Watanabe (Japan Display)

Discussion: None

Vote: 10 in favor and 0 opposed. **Motion passed.**

Action Item: SEMI staff to correct “Meeting Attendees” and “New Action Items # FPD M&C 140418-01” of the previous meeting minutes.

Attachment: 05_JA_FPD_M&C_&_Metrology_Previous_Mtg_Minutes_141030

6 Ballot Review

6.1 Doc.#5550, New Standard: Guide for Measuring Dimensions for Plastic Films/Substrates.

This document passed committee review and will be forwarded to the ISC A&R SC for procedural review.

Action Item: SEMI staff to forward adjudication result of Doc.#5550 to the ISC A&R Subcommittee for procedural review.

Attachment: 06_Ballot_Report_for_5550_141030

6.2 Doc.#5696, Reapproval of SEMI D9-0303 (Reapproved 0709), Terminology for FPD Substrates.

This document passed committee review and will be forwarded to the ISC A&R SC for procedural review.

Action Item: SEMI staff to forward adjudication result of Doc.#5696 to the ISC A&R Subcommittee for procedural review.

Attachment: 07_Ballot_Report_for_5696_141030

7 Task Force Reports

7.1 Polarizing Film Task Force

Yoshi Shibahara reported for the Polarizing Film Task Force. The Task Force met earlier in the day. Of note:

- Working for Doc. #5555, Revision to SEMI D50-0707, Test Method for Surface Hardness of FPD Polarizing Film.
- Discussing potential new business among the co-leaders continuously.
- In the immediate future, maintenance of the existing standards will be the major work items.

Attachment: 08_Polarizing_Film_TF_Report_141030

7.2 Backlight Task Force

No report was provided by the Task Force. SEMI asked the co-leaders whether the TF activities should be continued, and Satoshi Kanazawa, Stanley Electric, told that the TF should be disbanded once, since there are not new business as of present.

Motion: To disband the Backlight Task Force.
By / 2nd: Yoshi Shibahara (Fujifilm) / Ryoichi Watanabe (Japan Display)
Discussion: None
Vote: 9 in favor and 0 opposed. **Motion passed.**

7.3 Flexible Display Task Force

Tadahiro Furukawa reported on progress for the Flexible Display Task Force. The Task Force met earlier in the day. Of note:

- *Doc.#5550, New Standard: Guide for Measuring Dimensions for Plastic Films/Substrates, and Doc.#5696, Reapproval of SEMI D9-0303 (Reapproved 0709), Terminology for FPD Substrates*, passed committee review as previously discussed. (See 6).
- Working for *Doc. #5551, New Standard: Test Method for Measurement of Water Vapor Transmission Rate for Plastic Films and Sheets with High Barrier Properties for Electronic Devices*. Taiwan TC Chapter is also discussing the issues of barrier properties and a small meeting was held between Taiwan and Japan in October. It would be collaborated to make this standards document in the future.

7.4 Color Filter Task Force

Tadahiro Furukawa reported for the Color Filter Task Force that there were no particular things should be reported.

7.5 FPD Mask Task Force

Kazuya Shiojiri reported for the FPD Mask Task Force. Of note:

- 4 new SNARF was presented to the committee for approval.

Motion: To approve a new SNARF for “*Reapproval of SEMI D20-0706 Terminology for FPD Mask Defect*” and to submission it for Cycle 8, 2014 (#5796)

By / 2nd: Kazuya Shiojiri (SK Electronics) / Ryoichi Watanabe (Japan Display)

Discussion: None.

Vote: 9 in favor and 0 opposed. **Motion passed.**

Motion: To approve a new SNARF for “*Reapproval of SEMI D21-0706 Terminology for FPD Mask Pattern Accuracy*” and to submission it for Cycle 8, 2014 (#5797)

By / 2nd: Kazuya Shiojiri (SK Electronics) / Ryoichi Watanabe (Japan Display)

Discussion: None.

Vote: 9 in favor and 0 opposed. **Motion passed.**

Motion: To approve a new SNARF for “*Reapproval of SEMI D42-0308 Specification for Ultra Large Size Mask Substrate Case*” and to submission it for Cycle 8, 2014 (#5798)

By / 2nd: Kazuya Shiojiri (SK Electronics) / Ryoichi Watanabe (Japan Display)

Discussion: None.

Vote: 9 in favor and 0 opposed. **Motion passed.**

- Motion:** To approve a new SNARF for “*Reapproval of SEMI D53-0308 Specification for Liquid Crystal Display (LCD) Pellicles*” and to submission it for Cycle 8, 2014 (#5799)
- By / 2nd:** Kazuya Shiojiri (SK Electronics) / Ryoichi Watanabe (Japan Display)
- Discussion:** None.
- Vote:** 9 in favor and 0 opposed. **Motion passed.**
- Action Item:** SEMI Staff to submit reapproval ballot of SEMI D20 (#5796)for Cycle 8, 2014
- Action Item:** SEMI Staff to submit reapproval ballot of SEMI D21 (#5797)for Cycle 8, 2014
- Action Item:** SEMI Staff to submit reapproval ballot of SEMI D42 (#5798) for Cycle 8, 2014
- Action Item:** SEMI Staff to submit reapproval ballot of SEMI D53 (#5799) for Cycle 8, 2014
- Attachment:** 09_FPD_Mask_SNARF_SEMI_D20_(#5796)_141030
- Attachment:** 10_FPD_Mask_SNARF_SEMI_D21_(#5797)_141030
- Attachment:** 11_FPD_Mask_SNARF_SEMI_D42_(#5798)_141030
- Attachment:** 12_FPD_Mask_SNARF_SEMI_D53_(#5799)_141030

8 Old Business

8.1 Previous Meeting Action Items

Naoko Tejima reviewed the previous meeting action items.

Table 7 Previous Meeting Actions Items

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>
FPD M&C 140214-01	Flexible Display Task Force	To submit Doc. #5550, “New Standard: Guide for Dimensional Measurement of Plastic Films”, for Cycle 3, 2014 ... Close
FPD M&C 140214-03	SEMI Staff	To make the SNARF and to submit reapproval ballot of SEMI D9, Terminology for FPD Substrates, for Cycle 3, 2014 ... Close
FPD M&C 140418-01	SEMI Staff	To contact co-leaders of Backlight TF and ask them about their opinion whether the TF activities should be continued or not. ... Close

9 New Business

None.

[Japan FPD Metrology Committee Part]

10 Review of Previous Meeting Minutes

The committee reviewed the minutes of the previous meeting held on April 18, 2014.

It was pointed the following item should be changed.

- Meeting Attendees: “Haruhiko Itoh, Teijin” should be corrected to “Takashi Shiro, Teijin”.

- Motion:** To approve the minutes of the previous meeting as written after the above point is corrected.
- By / 2nd:** Yoshi Shibahara (Fujifilm) / Tadahiro Furukawa (Yamagata University)
- Discussion:** None
- Vote:** 10 in favor and 0 opposed. **Motion passed.**
- Action Item:** SEMI staff to correct “Meeting Attendees” of the previous meeting minutes.
- Attachment:** 04_JA_FPD_M&C_&_Metrology_Previous_Mtg_Minutes_141030

11 Task Force Reports

11.1 D31 Revision Task Force

Naoko Tejima reported on progress for the *D31 Revision* Task Force on behalf of Keizo Ochi, co-leaders. Of note:

- *Doc.#5685, Line Item Revision to SEMI D31-0213, Definition of Measurement Index (DSEMU) for Luminance Mura in FPD Image Quality Inspection* was published in September.
- TF will discuss about new business before it will be disbanded.

12 Old Business

12.1 Previous Meeting Action Items

Naoko Tejima reviewed the previous meeting action items.

Table 8 Previous Meeting Actions Items

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>
FPD MET 140418-01	SEMI Staff	To forward adjudication result of Doc.5685 to the ISC A&R Subcommittee for procedural review. ... Close

13 New Business

None.

[Common Part 2]

14 Action Item Review

14.1 New Action Items

Naoko Tejima reviewed the new action items. These can be found in the New Action Items table at the beginning of these minutes.

15 Next Meeting and Adjournment

The next meeting of the FPD Materials & Components Japan TC Chapter is scheduled for Friday, February 6, 2015, 15:00-17:00, SEMI Japan, Tokyo, Japan

The next meeting of the FPD Metrology Japan TC Chapter is scheduled for Friday, April 10, 2015, 14:00-17:00, SEMI Japan, Tokyo, Japan.

Respectfully submitted by:
 Naoko Tejima
 Manager, Standards
 SEMI Japan
 Phone: +81.3.3222.5804
 Email: ntejima@semi.org

Minutes approved by:

Tadahiro Furukawa (Yamagata University), Co-chair of FPD Materials & Components Japan TC Chapter	Jan. 6, 2015
Yoshi Shibahara (Fujifilm), Co-chair of FPD Materials & Components Japan TC Chapter	Jan. 1, 2015
Ryoichi Watanabe (Japan Display), Co-chair of FPD Metrology Japan TC Chapter	Jan. 6, 2015
Akira Kawaguchi (Otsuka Electronics), Co-chair of FPD Metrology Japan TC Chapter	Jan. 5, 2015

Table 9 Index of Available Attachments #1

#	<i>Title</i>
1	SEMI_Staff_Report_141030
2	Task_Force_Operation_Guideline_141030
3	KR_FPD_Liaison_Report_141030
4	TW_FPD_Liaison_Report_141030
5	JA_FPD_M&C_& Metrology_Previous_Mtg_Minutes_141030
6	Ballot_Report_for_5550_141030
7	Ballot_Report_for_5696_141030
8	Polarizing_Film_TF_Report_141030
9	FPD_Mask_SNARF_SEMI_D20_(#5796)_141030
10	FPD_Mask_SNARF_SEMI_D21_(#5797)_141030
11	FPD_Mask_SNARF_SEMI_D42_(#5798)_141030
12	FPD_Mask_SNARF_SEMI_D53_(#5799)_141030

#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at www.semi.org. For additional information or to obtain individual attachments, please contact Naoko Tejima at the contact information above.